

Embedded Systems: An Application-Centered Approach

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Two major sources of changing problems

New implementation technologies.

New applications.

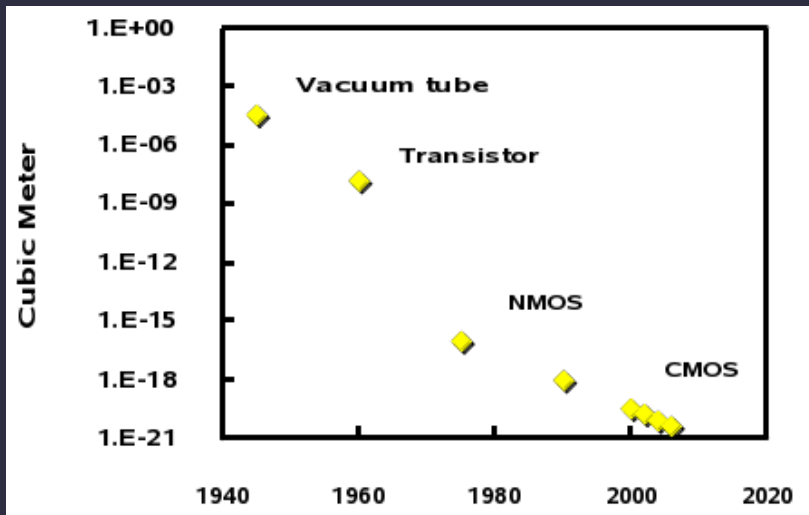
Outline

1. Evolution of computation
2. Carbon nanotubes
3. Single-electron tunneling transistors

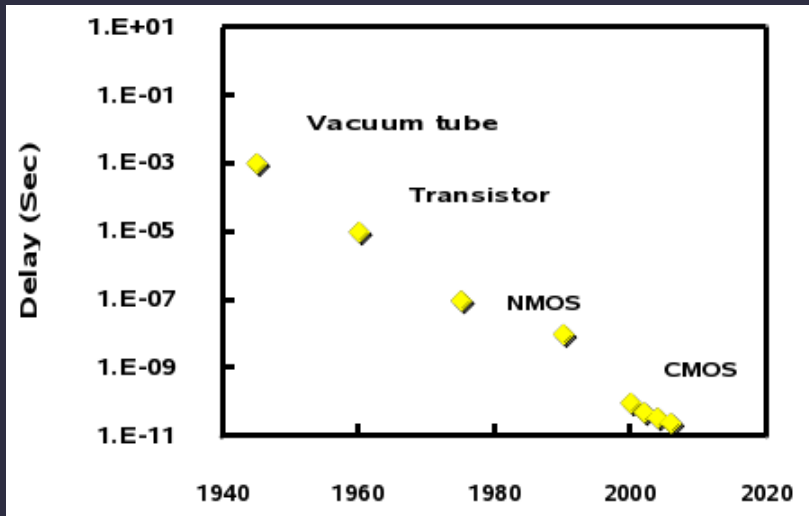
Evolution of computation

- 1800s: Mechanical
- Late 1800s–early 1900s: Electro-mechanical
- Early 1900s–mid 1900s: Vacuum tube electronic
- Mid 1900s–late 1900s: Bipolar (TTL)
- Late 1900s–early 2000s: MOS

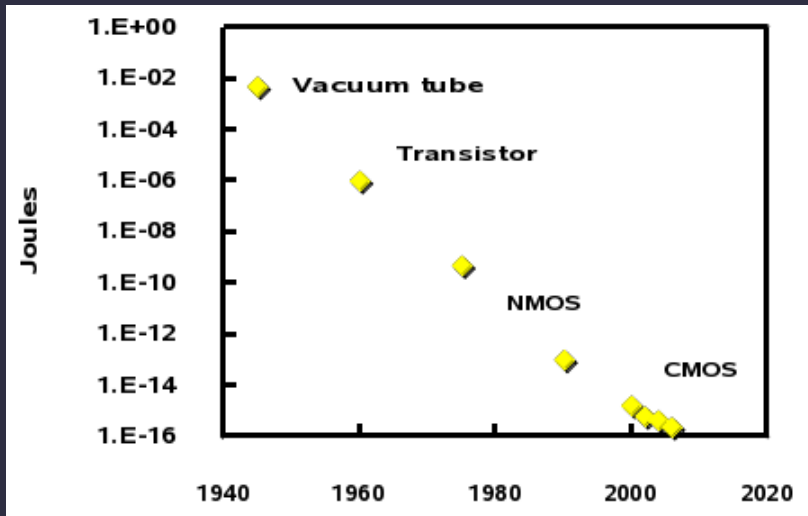
Impact of scaling on volume



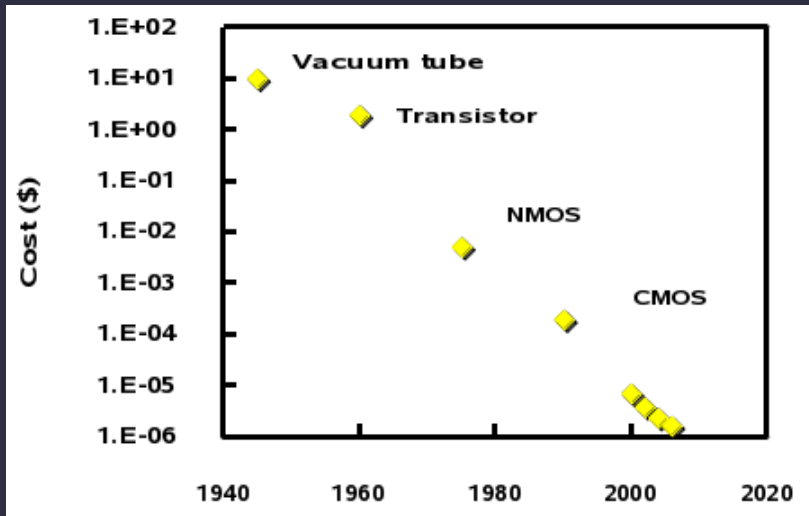
Impact of scaling on delay



Impact of scaling on energy consumption



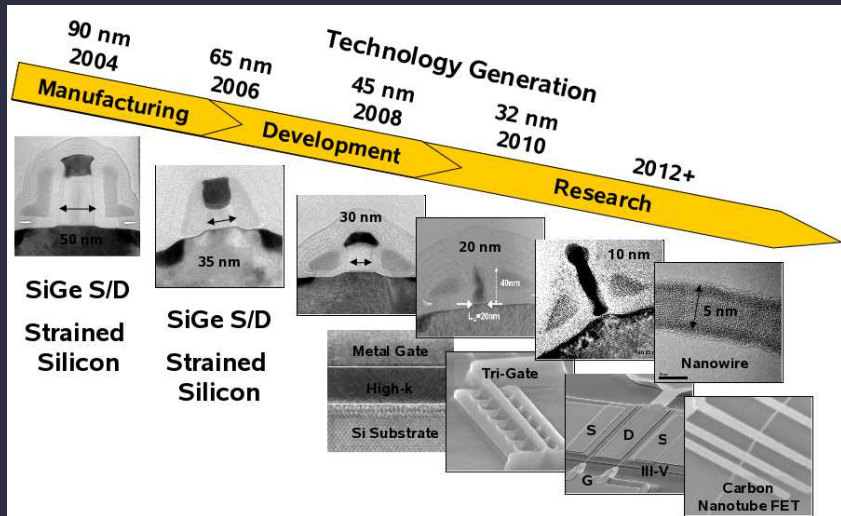
Impact of scaling on price



Scaling trends

| High Volume Manufacturing | 2004 | 2006 | 2008 | 2010 | 2012 | 2014 | 2016 | 2018 |
|---------------------------|------------------|------|-----------------------------|-------------------------------|------|------------------|------|------|
| Technology Node (nm) | 90 | 65 | 45 | 32 | 22 | 16 | 11 | 8 |
| Integration Capacity (BT) | 2 | 4 | 8 | 16 | 32 | 64 | 128 | 256 |
| Delay = CV/I scaling | 0.7 | ~0.7 | >0.7 | Delay scaling will slow down | | | | |
| Energy/Logic Op scaling | >0.35 | >0.5 | >0.5 | Energy scaling will slow down | | | | |
| Bulk Planar CMOS | High Probability | | | | | Low Probability | | |
| Alternate, 3D etc | Low Probability | | | | | High Probability | | |
| Variability | Medium | | | High | | Very High | | |
| Inter-lr dielectric k | ~3 | <3 | Reduce slowly towards 2-2.5 | | | | | |
| RC Delay | 1 | 1 | 1 | 1 | 1 | 1 | 1 | 1 |
| Metal Layers | 6-7 | 7-8 | 8-9 | 0.5 to 1 layer per generation | | | | |

Device trends



Advantages of CMOS relative to prior technologies

- Performance
- Gain, low noise
- Area
- Massive integration
- Power
- Reliability
- Fabrication difficulty & cost

Current status for CMOS

- 32 nm
- Power, thermal problems severe
- Fabrication cost per design high
- Potential reliability problems in future
- Soft errors
- Electromigration, dielectric breakdown, etc.
- Process variation
- Soon: Discrete dopant problems

Computing trends applications

- Increased market volume and size for portable and embedded systems compared to general-purpose computers.
- Instructor's opinion: Embedded will grow in importance in the future.
- High-performance general-purpose computing will still matter.
- Much of the general-purpose computation will move to data centers.








Advantages of alternative nanotechnologies

May allow continued process scaling after CMOS scaling impractical.

- Candidates
- Carbon nanotube
- Nanowire Single electron tunneling transistors

Comparison of nanoscale technologies

Table 59 Emerging Research Logic Devices—Demonstrated Projected Parameters


| Device | |  |  |  |  |  |  |  |
|--|--------------|---|--|---|---|---|--|---|
| | | FET [B] | 1D structures | Resonant Tunneling Devices | SET | Molecular | Ferromagnetic logic | Spin transistor |
| Types | | Si CMOS | CNT FET NW FET NW hetero-structures Crossbar nanostructure | RTD-FET RTT | SET | Crossbar latch Molecular transistor Molecular QCA | Moving domain wall M: QCA | Spin transistor |
| Supported Architectures | | Conventional | Conventional and Cross-bar | Conventional and CNN | CNN | Cross-bar and QCA | CNN Reconfigure logic and QCA | Conventional |
| Cell Size (spatial pitch) | Projected | 100 nm | 100 nm [C] | 100 nm [C] | 40 nm [L] | 10 nm [Q] | 140 nm [U] | 100 nm [C] |
| | Demonstrated | 590 nm | ~1.5 μm [D] | 3 μm [H] | ~700 nm [M] | ~2 μm [R] | 250 nm [V, W] | 100 μm [X] |
| Density (device/cm ²) | Projected | 1E10 | 4.5E9 | 4.5E9 | 6E10 | 1E12 | 5E9 | 4.5E9 |
| | Demonstrated | 2.8E8 | 4E7 | 1E7 | 2E8 | 2E7 | 1.6E9 | 1E4 |
| Switch Speed | Projected | 12 THz | 6.3 THz [E] | 16 THz [I] | 10 THz [M] | 1 THz [S] | 1 GHz [U] | 40 GHz [Y] |
| | Demonstrated | 1 THz | 200 MHz [F] | 700 GHz [J] | 2 THz [N] | 100 Hz [R] | 30 Hz [V, W] | Not known |
| Circuit Speed | Projected | 61 GHz | 61 GHz [C] | 61 GHz [C] | 1 GHz [L] | 1 GHz [Q] | 10 MHz [U] | Not known |
| | Demonstrated | 5.6 GHz | 220 GHz [G] | 10 GHz [Z] | 1 MHz [F] | 100 Hz [R] | 30 Hz [V] | Not known |
| Switching Energy, J | Projected | 3E-18 | 3E-18 | >3E-18 | 1 × 10 ⁻¹⁸ [L] >1.5 × 10 ⁻¹⁷ [O] | 5E-17 [T] | ~1E-17 [V] | 3E-18 |
| | Demonstrated | 1E-16 | 1E-11 [G] | 1E-13 [K] | 8 × 10 ⁻¹⁷ [P] >1.3 × 10 ⁻¹⁴ [O] | 3E-7 [R] | 6E-18 [W] | Not known |
| Binary Throughput, GBit/ns/cm ² | Projected | 238 | 238 [C] | 238 [C] | 10 | 1000 | 5E-2 | Not known |
| | Demonstrated | 1.6 | 1E-8 | 0.1 | 2E-4 | 2E-9 | 5E-8 | Not known |
| Operational Temperature | | RT | RT | 4.2 – 300 K | 20 K [L] | RT | RT | RT |
| Materials System | | Si | CNT, Si, Ge, III-V, In ₂ O ₃ , ZnO, TiO ₂ , SiC, | III-V Si-Ge | III-V Si | Organic molecules | Ferromagnetic alloys | Si, III-V, complex metals oxides |
| Research activity [A] | | | 171 | 88 | 65 | 204 | 25 | 102 |

Credit to ITRS'05 report on Emerging Research Devices.

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Carbon

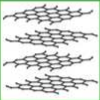


allotropes

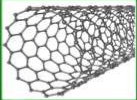
diamond




graphite




carbon nanotube




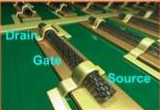
Fullerene



applications



nanotechnology



CNT history



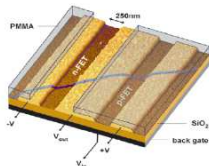
Edison's original
carbon-filament lamp
US Patent 223898

1880



Discovery of Fullerenes
(Smalley)

1985



Carbon nanotube transistor
based logic-performing ICs (IBM)

2001

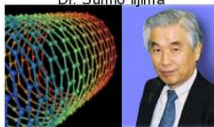
1978

F/A-18 Hornet
The first aircraft with
carbon fiber wings



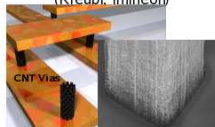
1991

Nanotubes discovered at
NEC, by Japanese researcher
Dr. Sumio Iijima

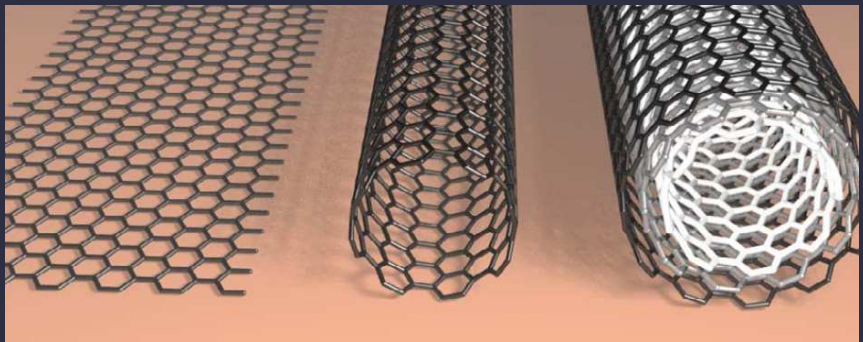


2002

Carbon nanotubes in
interconnect applications
(Kreupl, Infineon)



CNT classes

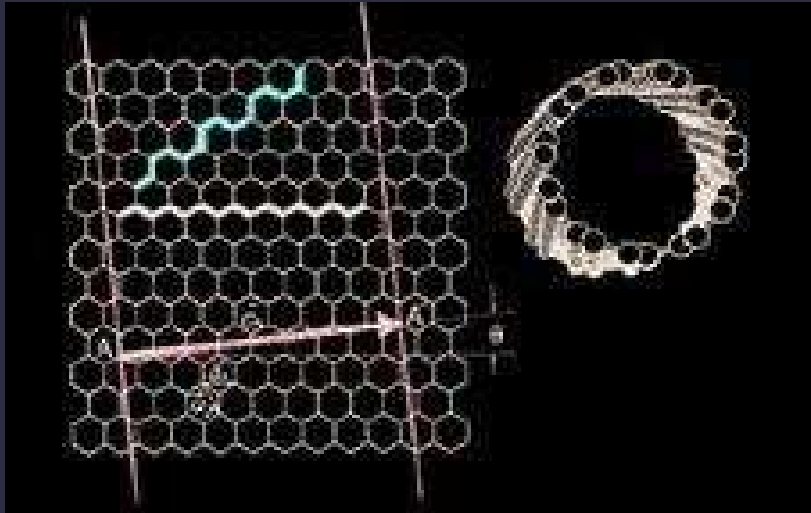


Graphene

Single-walled CNT

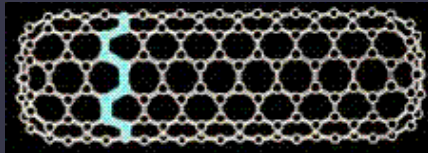
Multi-walled CNT

Chirality



Metallic and semiconducting CNTs

Armchair (metallic)



Zigzag (semi-conducting)



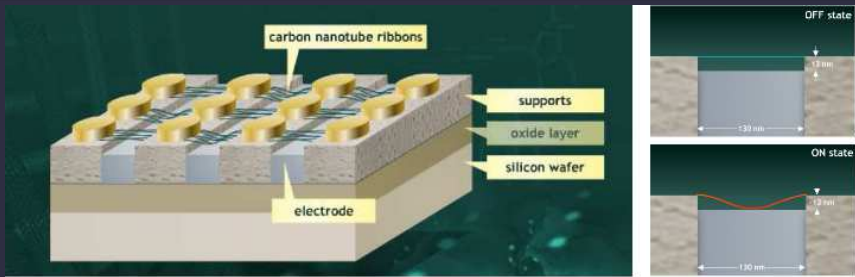
CNT properties

- Metallic or semiconducting.
- Diameter: 0.4–100 nm.
- Length: up to millimeters.
- Ballistic transport.
- Excellent thermal conductivity.
- Very high current density.
- High chemical stability.
- Robust to environment.
- Tensile strength: 45 TPa.
 - Steel is 2 TPa.
- Temperature stability
 - 2,800°C in vacuum.
 - 700°C in air.

CNTs compared with Cu

| Property | CNT | Cu |
|----------------------------------|--|-----------------|
| Max I dens. (A/cm ²) | $> 1 \times 10^9$ (Wei et al., APL'01) | 1×10^7 |
| Thermal cond. (W/mK) | 5,800 (Hone et al., Phy Rev B'99) | 385 |
| Mean free path (nm) | $> 1,000$ (McEuen et al. T Nano'02) | 40 |

NRAM



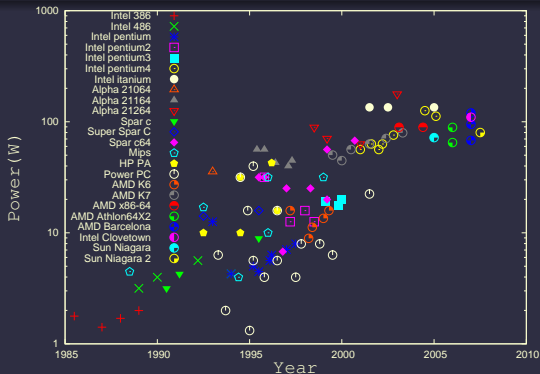
- Uses Van der Waals forces.
- Non-volatile.
- SRAM-like speed.
- DRAM-like density.
- Ready for market in 2007 (and 2008, and 2009, and 2010, and 2011).
- IEEE Spectrum loser of the year. Why?

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Power challenges

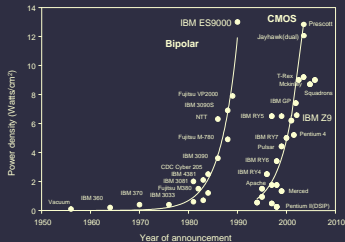
High-performance applications: energy cost, temperature, reliability
Portable embedded systems: battery lifetime



What does history teach us about power consumption?

Device innovations have been the most effective method

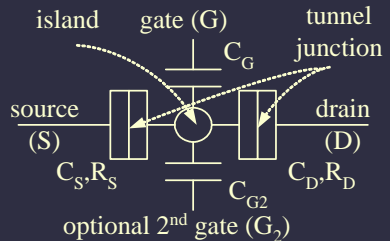
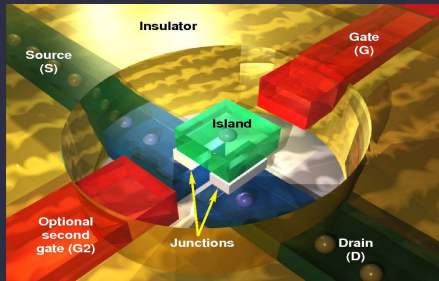
- Vacuum tube to semiconductor device in the 1960s
- Bipolar device to CMOS transistor in the 1990s



Single electron tunneling transistor structure

Device structure

- Island, terminals (source, drain, gate)
- Electron tunneling through tunneling junctions



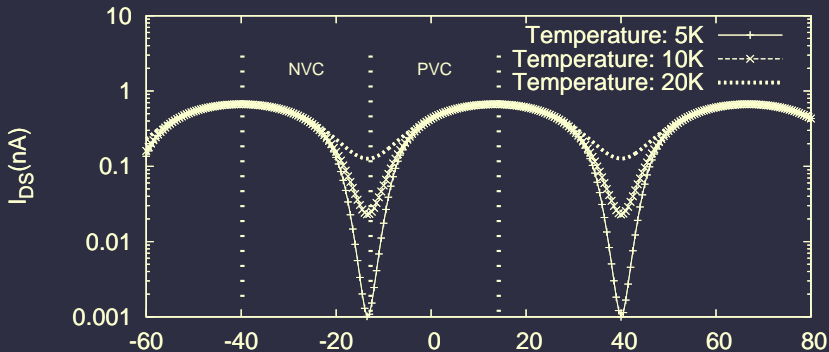
C_G : gate capacitance
 C_{G2} : optional 2nd gate capacitance
 C_S : source tunnel junction capacitance

C_D : drain tunnel junction capacitance
 R_S : source tunnel junction resistance
 R_D : drain tunnel junction resistance

Single electron tunneling transistor behavior

Physical principles

- Coulomb charging effect governs electron tunneling
- Coulomb blockade $V_{GS} = me/C_G$, $m = \pm 1/2, \pm 3/2, \dots$ OFF, $m = 0, \pm 1, \pm 2, \dots$ ON



SET properties and challenges

Ultra low power

- Projected energy per switching event (1×10^{-18} J)

Room temperature and fabrication challenge

- Electrostatic charging energy must be greater than thermal energy
- $e^2/C_{\Sigma} > k_B T$
- Requires $e^2/C_{\Sigma} > 10k_B T$ or even $e^2/C_{\Sigma} > 40k_B T$

SET properties and challenges

Performance challenge

- Electrons must be confined in the island
- $R_S, R_D > h/e^2$, $h/e^2 = 25.8 \text{ k}\Omega$
- High resistance, low driving strength

Reliability concerns

- Tunneling between charge traps cause run-time errors
- Unknown before fabrication
- Device technology: Improved by silicon islands
- Reliable design: Post-fabrication adaptation
- Run-time error correction

Summary

- CMOS will be mainstream for years to come, but not forever.
- The meaning of integrated circuits will change in the future.
- Circuit and logic design fundamentals will still apply.
- Some rules, e.g., difficulty of implementing non linearly separable functions, may change.
- You will each need to adapt as the rules governing device behavior change, but this will be much faster now that you have a foundation.